



Docket No.: 49657

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
	:	
Kenji ITOGA, et al.	:	Confirmation Number: 5521
	:	
Application No.: 09/769,490	:	Group Art Unit: 2882
	:	
Filed: January 26, 2001	:	Examiner: Kao, Chih Cheng G.
	:	
For:	:	
X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE		

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Notice of Allowance and Notice of Allowability dated January 12, 2005.